Development of an Atomic Layer Etching process dedicated to diamond material

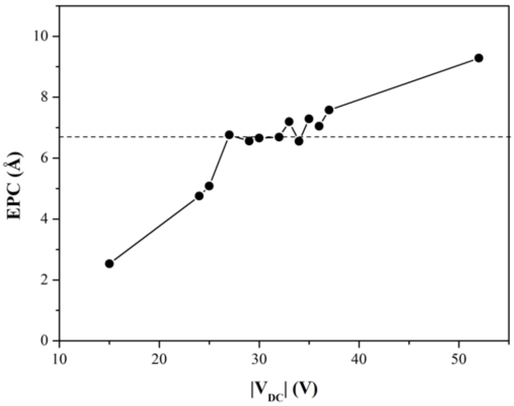

Figure 1 –Etching rate Per Cycle for the ALE process, vs self-bias voltage.